



PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No.: 09/361,980  
Filing Date: July 28, 1999  
Applicant: Yasuaki Tsuzuki et al.  
Group Art Unit: 1765  
Examiner: Lynette T. Umez-Eronini  
Title: Method of Etching Metallic Thin Film On Thin Film Resistor  
Attorney Docket: 4041J-000439

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P.O. Box 1450  
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AMENDMENT

Sir:

In response to the Office Action mailed June 20, 2003, Paper No. 21, please amend the application as follows and consider the remarks set forth below.

**Amendments to the Claims** begin on page 2 of this paper.

**Remarks** begin on page 7 of this paper.